

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant :	Masaharu Nagai et al.	Art Unit :	1756
Serial No. :	10/694,986	Examiner :	Daborah Chacko Davis
Filed :	October 29, 2003	Conf. No. :	5334
Title :	METHOD FOR REMOVING RESIST PATTERN AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE		

MAIL STOP AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

REPLY TO ACTION OF APRIL 5, 2007

Please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 8 of this paper.